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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**INFORMATION DISCLOSURE  
STATEMENT (PTO 1449)**

ATTORNEY DOCKET NO.

**70020.0079USWO**

U. S. APPLICATION SERIAL NO.

**To Be Assigned**

CONFIRMATION NO

**N/A**

BASED ON INTERNATIONAL APPLICATION NO.

**PCT/JP2005/009128**

INTERNATIONAL FILING DATE

**May 19, 2005**

INVENTOR(S)

**Takashi MIYAMATSU, et al.**

EXAMINER

**Not Assigned**

GROUP ART UNIT

**N/A**

TITLE OF APPLICATION

**LIQUID FOR IMMERSION EXPOSURE AND IMMERSION EXPOSURE METHOD**

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A	5,817,256	10/06/1998	WEIPPERT	/		
	B	US 2002/0006675 A1	01/17/2002	SHIGARAKI			
	C	US 2004/0242825 A1	12/02/2004	SHISHIDO ET AL.			

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	D	JP 11-176727	07/02/1999	JAPAN	/		Abstract	
	E	JP 10-303114	11/13/1998	JAPAN			Abstract	
	F	JP 2003-160515	06/03/2003	JAPAN			Abstract	
	G	JP 2001-181217	07/03/2001	JAPAN			Abstract	
	H	JP 60-209536	10/22/1985	JAPAN			Abstract	
	I	JP 2004-123762	04/22/2004	JAPAN			Abstract	
	J	JP 2002-255866	09/11/2002	JAPAN			Abstract	
	K	JP 06-12452	02/16/1994	JAPAN				X
	L	JP 09-241214	09/16/1997	JAPAN			Abstract	
	M	JP 07-220990	08/18/1995	JAPAN			Abstract	
	N	JP 2001-326162	11/22/2001	JAPAN			Abstract	
	O	WO99/49504	09/30/1999	WIPO			Abstract	
	P	AU 2747999	10/18/1999	AUSTRALIA			Abstract	
	Q	WO03/016365	02/27/2003	WIPO			Abstract	
	R	WO01/032739	05/10/2001	WIPO			Abstract	
	S	JP 62-094813	05/01/1987	JAPAN			Abstract	

EXAMINER

/Peter Kim/

DATE CONSIDERED

03/16/2009

EXAMINER: Initial if the reference is considered, whether or not the citation is in conformance with MPEP 609. Draw a line through the citation if it is not in conformance and it is not considered. Include a copy of this form with the next communication to the Applicant.

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		U.S. APPLICATION SERIAL NO. <b>To Be Assigned</b>	CONF. NO. <b>N/A</b>
		BASED ON INTERNATIONAL APPLICATION NO. <b>PCT/JP2005/009128</b>	
INVENTOR(S) <b>Takashi MIYAMATSU, et al.</b>	EXAMINER (If known) <b>Not Assigned</b>	INTERNATIONAL FILING DATE <b>May 19, 2005</b>	ART UNIT (If known) <b>N/A</b>

FOREIGN PATENT DOCUMENTS							
	T	JP 2001-068400	03/16/2001	JAPAN	<del>/</del>		Abstract
	U	JP 11-233402	08/27/1999	JAPAN	<del>/</del>		Abstract
	V	JP 2005-072230	03/17/2005	JAPAN	<del>/</del>		Abstract

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
W	Inside Memory, Nikkei Microdevice, p. 77-86 (April 2004).
X	Smith, et al., Approaching the numerical aperture of water-Immersion lithography at 193nm, Proc. SPIE, Vol. 5377, pp. 273-284 (2004).
Y	Sylvester-Hvid, et al., Refractive Indices of Molecules in Vapor and Liquid: Calculations on Benzene, J. Phys. Chem. A, Vol. 103, No. 42, pp. 8447-8457 (1999).
Z	Immersion Lithography Modeling 2003 year-End Report (International SEMATECH).
AA	The seminar text of special seminar on immersion exposure technology, pp. 14-33 (May 27, 2004).

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